



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Vyvoda et al.	
Application No.: 09/776009	Group Art Unit: 2814
Filed: 02/02/2001	Examiner: Anh D. Mai
Title: Wafer Surface that Facilitates Particle Removal	
Attorney Docket No.: MA-027	
Assistant Commissioner for Patents PO Box 1450 Alexandria VA 22313-1450	

**REQUEST FOR CONTINUE EXAMINATION**

Applicants request continued examination under 37 CFR 1.114. The claim amendments and remarks included herein constitute the required submission.

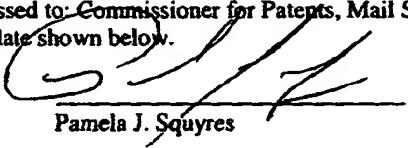
**CLAIM AMENDMENTS**

Please amend claims 1, 30, and 44 as in the following list of current claims.

Please cancel claims 6, 35, and 49. Please add new claims 57-62.

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, Mail Stop RCE, PO Box 1450, Alexandria VA 22313-1450 on the date shown below.

7/23/03  
Date

  
Pamela J. Squyres